Pump

out Gas

Application No: Unknown

,116a RF 118a **Process Gases** ¥ 100 Match Box and **Diplexer** 102 Power 114 110 -110 108 -108 -104 120 -120

106

116b

FIG. 1A (Prior Art)

Match Box and Diplexer

112

118b

Pump

out Gas

RF Power

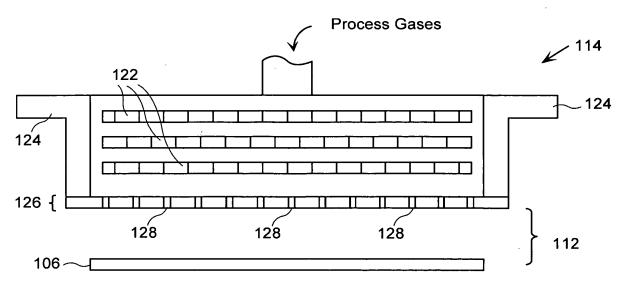
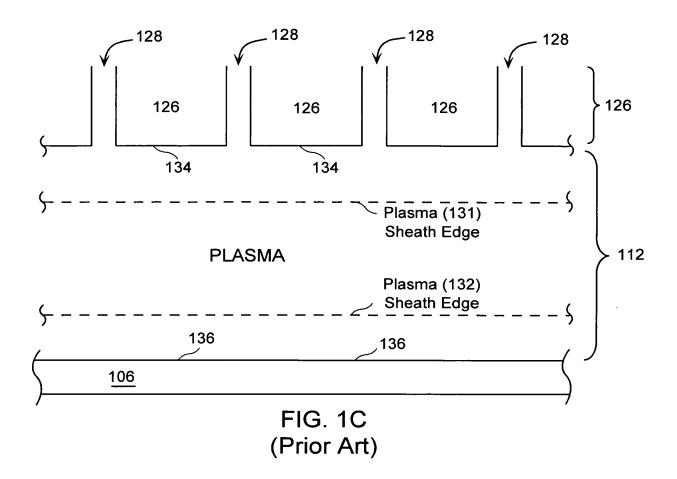
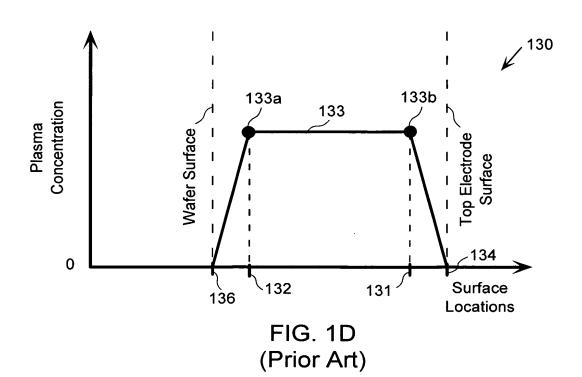


FIG. 1B (Prior Art)





Title: SEMICONDUCTOR PROCESS CHAMBER ELECTRODE

Inventors: KUTHI et al. Application No: Unknown Attorney Docket No: LAM1P077A2

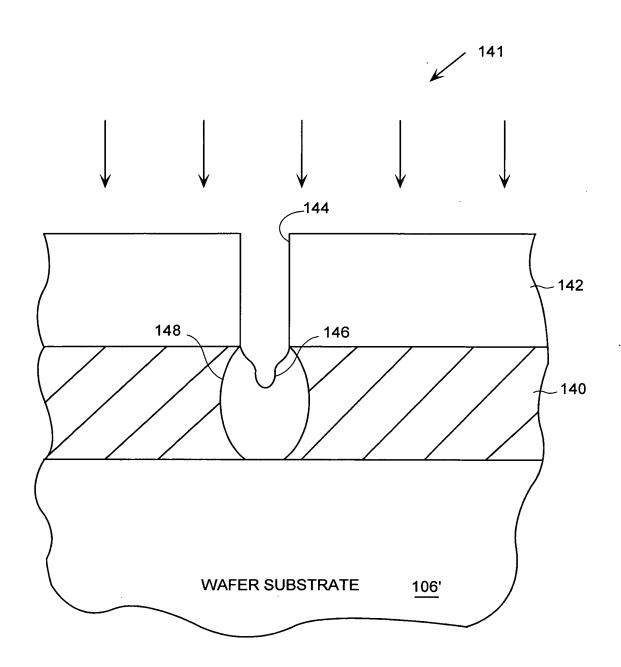
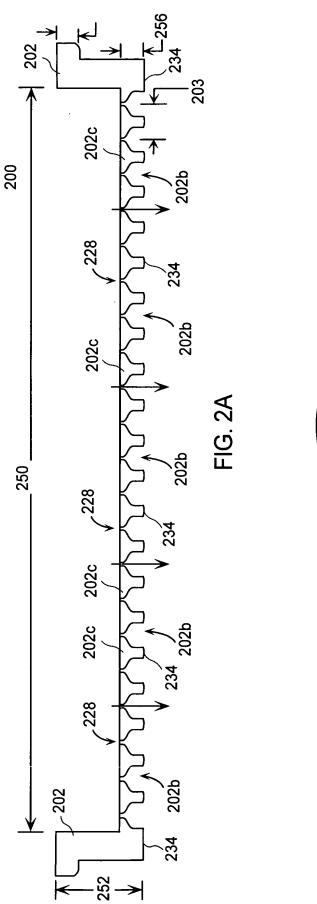
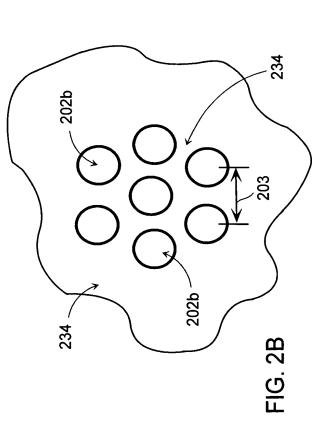
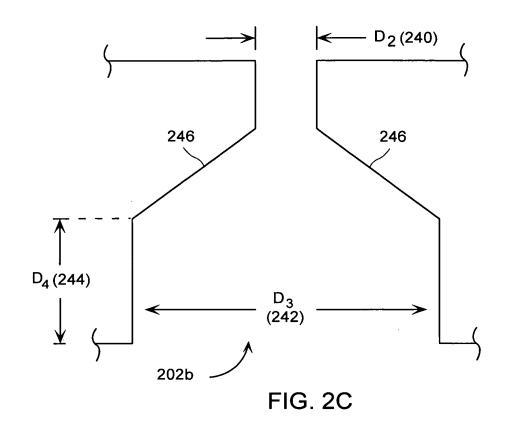


FIG. 1E (Prior Art)







248 D₅ (249) D₄ (244) D₃ (242) FIG. 2D

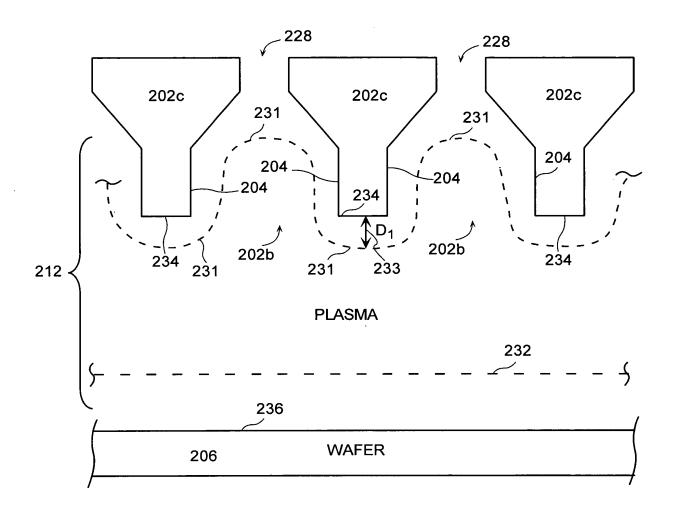
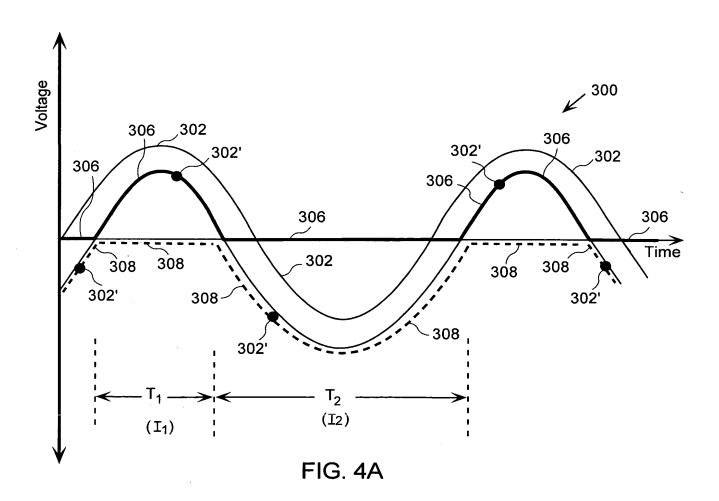


FIG. 2E



Title: SEMICONDUCTOR PROCESS CHAMBER ELECTRODE
Application No: Unknown Attorney Docket No: LAM1P077A2

inventors: KUTHI et al.

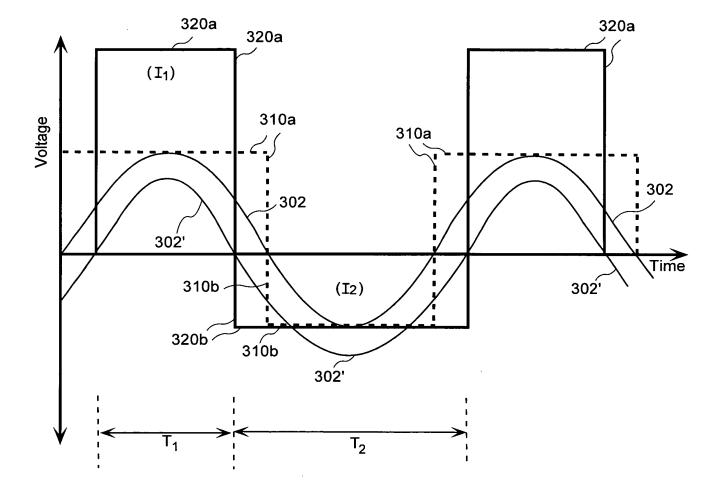


FIG. 4B

Application No: Unknown

Attorney Docket No: LAM1P077A2

Bias vs. Area Ratio

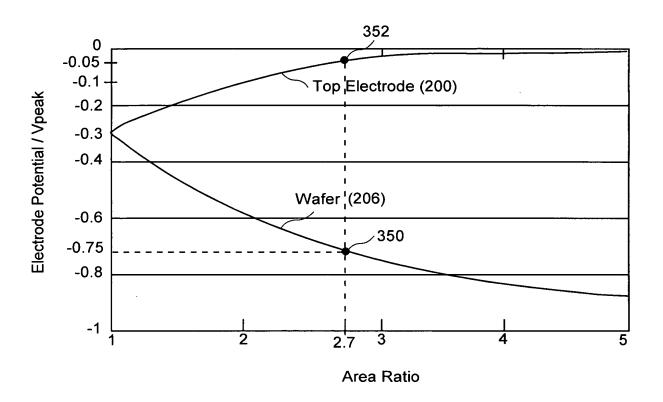


FIG. 5